

Title (en)
VACUUM-COATING INSTALLATION AND METHOD

Title (de)
VAKUUMBESCHICHTUNGSANLAGE UND VERFAHREN ZUR VAKUUMBESCHICHTUNG

Title (fr)
INSTALLATION DE REVETEMENT SOUS VIDE ET PROCEDE DE REVETEMENT SOUS VIDE

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Application
EP 05773105 A 20050708

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Abstract (en)
[origin: WO2006010451A2] The invention relates to an installation for vacuum-coating substrates, said installation comprising a vacuum chamber, a system for holding at least one substrate, and a transport device for transporting the substrate into the coating regions, at least one first coating region of the vacuum chamber being provided with at least one device for plasma impulse chemical vapour deposition (PICVD) and at least one second coating region of the vacuum chamber being provided with at least one device for sputter coating.

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Cited by
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